Equipment Spec BW 3000 F (L-->R)

POSITION NO			1	2	3	4	5	6	7	8	9	10	REMARK
Name			LOAD	CW/LTRAN	SPM	HQDR1	LAL	OF	SC1	HQDR2	RD(APET)	ULD/BUFFER	
ROBOT(Transfer Unit)													
Shutter Position													
Chemical In used		#1											
		#2											
		#3											
Mixing Ratio Range													
Processing Temperature(℃)													
Bath Material					Quartz	Quartz		Quartz	-	Quartz			
Bath Shape(Type)													
Bath Capacity(L)													
Wafer Guide Material													Wafer Guide (4EA)
Arm						Quartz		PEEK		Quartz		Quartz	
Material	Bath Lower Section												
	Chemical Supply Piping												
	Drain Piping												
Bath/Processing Functions.	Shower			-	-	-	-	-	-	-			
	N2 bubbling			-	-	-	-	-	-	-			
	Resistivity metere			-	-	-	-	-	-	-			
	Auto-cover			-	-	-	-	-	-	-			
	Megasonic			-	-	-	-	-	-	-			
	Bath Cleaning			-	-	-	-	-	-	-			
	Chemical/H2O Supply Function			-	-	-	-	-	-	-			
Temp Control	Electric therm-control			-	-	-	-	-	-	-			
	Heater			-		-	-	-	-	-			
Chemical/ DIW drain	Processing Bath	->Gravity		-	-	-	-	-	-	-			
		->Pump		-	-	-	-	-	-	-			
		->QDR		-	-	-	-	-	-	-			
		->Aspirator		-	-	-	-	-	-	-			
		->Cooling Tank/->Gravity		-	-	-	-	-	-	-			
	Drain switching			-	-	-	-	-	-	-			
	Drain Chemical Name #1			-	-	-	-	-	-	-			
	Drain Chemical Name #2			-	-	-	-	-	-	-			
Circulation	Pump			-	-	-	-	-	-	-			
				-	-	-	-	-	-	-			
	Filter			-		-	-	-	-	-			
				-		-	-	-	-	-			
	Housing												
	Pump controller												
Meatureing Tank	Material&Temp(℃)	#1		-									
		#2		-									
		#3											
	Replenishment (Pump,Level,Etc)	#1											
		#2											
		#3											
	Preheat(Heat)												
	Chemical/H2O Supply Function												

Application	Batch Wafer Processing						
Size of wafer	300mm						
System Power Rating	Main power	PHASE	VAC	UPS	PHASE	VAC	
	208V	3	150A	208V	3Ph	150A	

REMARK

Name	Model		Quantity	Remark
PC Controll Box				
Fire Extingushier			1	
PLC	Omron	Mitsubishi		
Agas monitory				
Inline Heater				
Hot DIW Unit	N/A			
Megasonic Unit			2	SC1,OF
Parts and Quartz box			8	
Concentration monitor unit	HORIBA CS-100		1	SC1
Drain Cooling Unit	N/A			
Process Direction	L--->R			